

CLAIMS

1. A microfiltration filter cartridge comprising a micro-porous filtration membrane, supports, a core, an outer cover and end plates, all the components being
5 formed of a polysulfone based polymer, wherein melting molding members in the component is subjected to annealing.
2. The microfiltration filter cartridge according to claim 1, wherein the melting molding members subjected
10 to the annealing is end plates.
3. The microfiltration filter cartridge according to claim 1 or 2, wherein all of the micro-porous filtration membrane, the supports, the core, the outer cover and the end plates which are the components are formed of
15 polyethersulfone.
4. The microfiltration filter cartridge according to any of claims 1 to 3, wherein a dimension in an axial direction of a window of each of the outer cover and the core is 1 mm to 3 mm.
- 20 5. The microfiltration filter cartridge according to any of claims 1 to 4, wherein a primary side and/or secondary side supports/support are/is formed by a micro-porous film provided with a large number of very fine concave portions and/or convex portions.
- 25 6. The microfiltration filter cartridge according to

any of claims 1 to 5, wherein the micro-porous filtration membrane has a water bubble point of 0.3 MPa or more and the supports has a water bubble point of 0.15 MPa or less.

7. A method of manufacturing a microfiltration filter cartridge comprising a micro-porous filtration membrane, supports, a core, an outer cover and end plates, all the components being formed of a polysulfone based polymer, wherein melting molding members in the component is subjected to annealing.

8. The method of manufacturing a microfiltration filter cartridge according to claim 7, wherein the melting molding members to be annealed is end plates.

9. The method of manufacturing a microfiltration filter cartridge according to claim 7 or 8, wherein all of the micro-porous filtration membrane, the supports, the core, the outer cover and the end plates which are the components are formed of polyethersulfone.

10. The method of manufacturing a microfiltration filter cartridge according to any of claims 7 to 9, wherein the cartridge is cleaned with a flow of warm ultrapure water at 50°C to 100°C after assembling and is then dried in a clean oven.

11. A method of filtrating a wafer cleaning solution for a semiconductor integrated circuit, wherein the microfiltration filter cartridge according to any of

claims 1 to 6 is used to start to filtrate chemicals without prewetting through alcohol.

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